

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Shen et al.	Group Art Unit: 1763
Application No: 09/507,629	Examiner: Allan W. Olsen
Confirmation No: 7912	Attorney Docket No:
Filed: 2/18/2000	001945 USA P 03/ETCH/SILICON/JB1
Title: SELF-CLEANING PROCESS FOR ETCHING SILICON-CONTAINING MATERIAL	September 30, 2003 San Francisco, California

AMENDMENT IN RESPONSE TO FINAL OFFICE ACTION

Commissioner for Patents

Via Facsimile
(703) 872-9311

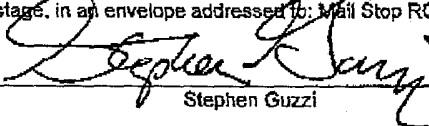
Examiner Olsen:

This communication is in response to the Office Action mailed on June 4, 2003, and is being timely filed within four months thereof with a request for a one-month extension of time.

Certificate of Transmission

I hereby certify that, on the date shown below, this correspondence is either being facsimile transmitted to the U.S. Patent and Trademark Office via Fax No. (703) 872-9311, or being deposited with the United States Postal Service as first class mail with sufficient postage, in an envelope addressed to: Mail Stop RCE, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

By:


Stephen Guzzi

Date:

September 30, 2003